



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION OF

Confirmation No.: 7680

VAN DER LAAN et al.

Group Art Unit: NOT ASSIGNED

Appln. No.: 09/943,088

Examiner: NOT ASSIGNED

Filed: August 31, 2001

Title: METHOD OF OPERATING A LITHOGRAPHIC APPARATUS, LITHOGRAPHIC APPARATUS, METHOD OF MANUFACTURING A DEVICE, AND DEVICE MANUFACTURED THEREBY

October 31, 2001

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**PRELIMINARY AMENDMENT**

Hon. Commissioner of Patents  
Washington, D.C. 20231

Sir:

Prior to the first Office Action on the merits, please amend the above-identified application as follows:

**IN THE CLAIMS:**

Please add the following new claim:

26. (New) A method of operating a lithographic projection apparatus comprising:  
forming at least one spot of radiation from at least a portion of a projection beam in the apparatus;

measuring a spatial variation in intensity of defocused radiation from said spot with at least one sensor, the at least one sensor being constructed and arranged to perform real time electronic analysis of an intensity distribution; and

determining properties of said apparatus from the measured spatial variation.